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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/825,504
Applicant : Volker Derflinger et al.
Filed : April 15, 2004
Title : "WORKPIECE WITH A HARD FILM OF ALCR-CONTAINING MATERIAL, AND PROCESS FOR ITS PRODUCTION"

Conf. No. : 8570
TC/A.U. : 3722

Customer No. : 00116
Docket No. : 35885US1

INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with Rule 56, applicants are aware of the publications listed in the enclosed copy of Patent Office Form 1449.

It is requested that these references be considered by the Examiner in the examination of the above-identified application.

A copy of the cited references is enclosed herewith.

If there are any further fees resulting from this communication not covered by the enclosed check, or if no check was enclosed, please charge the same to Deposit Account No. 16-0820, Order No. 35523US1.

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Michael W. Garvey
Name of Attorney for Applicant(s)

10-15-2004
Date

Signature of Attorney

Respectfully submitted,
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By 
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October 15, 2004

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BY APPLICANT

APPLICANT: Volker Derflinger et al.

FILING DATE:
April 15, 2004GROUP ART UNIT:
3722

U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Date	Name	Class	Subclass	Filing Date if Appropriate
	A						
	B						
	C						
	D						
	E						
	F						
	G						

FOREIGN PATENT DOCUMENTS

		Document No.	Date	Country	Class	Subclass	Translation
	H	1 186 681 A1	8/2001	EP			Cited in Spec.
	I	09-041127	8/1995	JP			Cited in Spec.
	J						
	K						

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

R	Thin films (Proc. 4 in. Sypos. Trends & New Applications of Thin Films 1993) DGM Info. Sges., Oberursel 1993, p 73.
S	Surface & Coatings Technology vol. 165, 2 (2003) p. 163-167. Oxidation Resistance of Cr _{1-x} A _x N and Ti _{1-x} A _x N films.
T	Surface & Coating Technoloy vol. 163-164 (2003) p. 57-61. High-Temperature Oxidation Resistance of Cr _{1-x} A _x N Thin Films Deposited by Reactive Magnetron Sputtering.
U	J. Vac. Sci. Technol. A 20(2), Mar/Apr 2002, p. 569-571. Microhardness and Lattice Parameter of Cr _{1-x} A _x N Films.
V	Surface & Coating Technology, vol. 163-164 (2003) p. 546-551. Abrasive Wear Tsting of DLC Coatings deposited on plane and Cylindrical Parts.
W	Tribologie-Fachtagung 2000, moers: Ges. F. Tribol. 2002, ISBN 3-00-003404-8, Investigations of Mechanical and Tribological Properties of CrAlN + C Thin Coatings Deposited on Cutting Tools.

Examiner:

Date Considered

*Examiner: Initial if reference considered, regardless of whether citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.